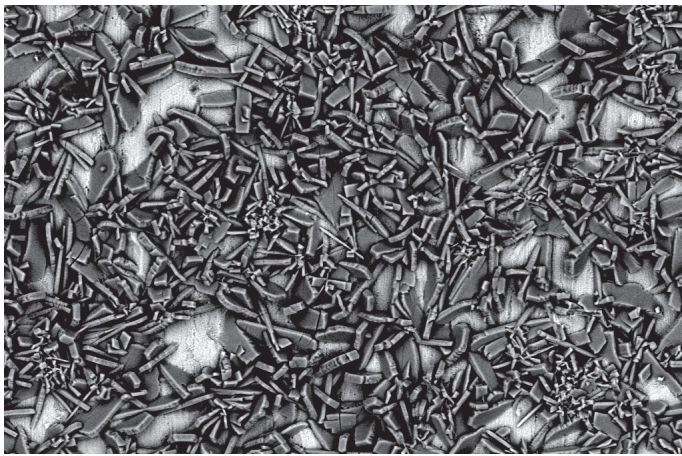


# Phenom ParticleX TC Desktop SEM

Multi-purpose desktop SEM enabling cleanliness at microscale





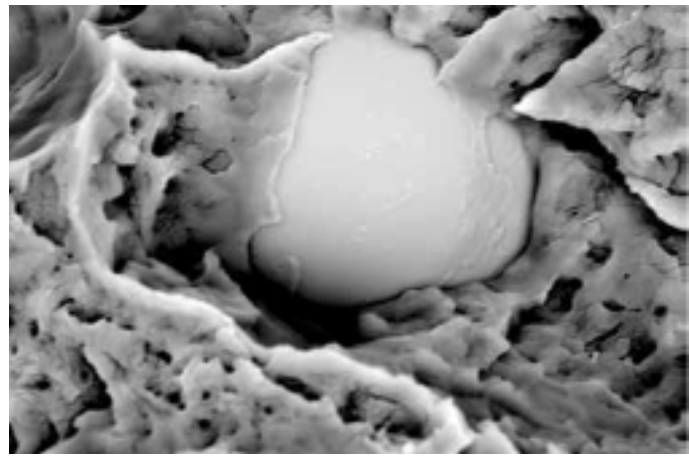
SEM image of Zinc-Phosphate on sheet metal

A growing number of manufacturing companies are establishing scanning electron microscopy (SEM) systems in-house. This trend, from outsourcing to in-house analysis, is growing and the benefits, such as the ability to perform a broad range of automated desktop analyses, chemical classification and verification according to specific norms are clear. Timely and accurate quality control are prerequisites for today's manufacturing. The Thermo Scientific™ Phenom™ ParticleX Desktop SEM is a versatile solution for high-quality analysis in-house. It gives you the ability to carry out speedy analysis, verification and classification of materials, supporting your production with fast, accurate and trusted data. The system is automated and offers multiple sample analysis, making testing and classification up to 10 times faster. Outsourcing typically takes up to 10 working days, whereas the Phenom ParticleX Desktop SEM gives you certainty within one day. The system is simple to operate and fast to learn, opening up the use of particle and material analysis to a wider group of users in-house. In addition to eliminating the need to outsource, the Phenom ParticleX Desktop SEM ease-of-use and automation allows you to offload sample analysis from other SEMs in your laboratory.

The Phenom ParticleX Desktop SEM not only provides high quality SEM analysis, it is also designed to perform a number of specific functions. These include particle analysis of metal powders at the microscale for the additive industry, and confirming that components fulfill technical cleanliness specifications according to VDA19 or ISO16232 standards. All now made possible in-house and on your desktop.

#### **Phenom ParticleX: general SEM usage**

The Phenom ParticleX Desktop SEM features a chamber which includes an accurate and fast motorized stage that allows analysis of samples of up to 100 mm x 100 mm. In spite of this larger sample size, a proprietary loading shuttle keeps the vent/load cycle to an industry-leading sample loading time of 40 seconds or less. In practice this improves the throughput factors higher than other SEM systems.



SEM image of undesired particle within polymeric matrix

The user interface is based on the proven ease-of-use technology applied in the successful Phenom desktop SEM products. The interface enables both existing and new users to quickly become familiar with the system with a minimum of training.

The standard detector in the Phenom ParticleX Desktop SEM is a four-segment backscattered electron detector (BSD) that yields sharp images and provides chemical contrast information together with a fully-integrated energy dispersive X-ray (EDX) system for elemental analysis. A secondary electron detector (SED) for surface sensitive imaging is optional.

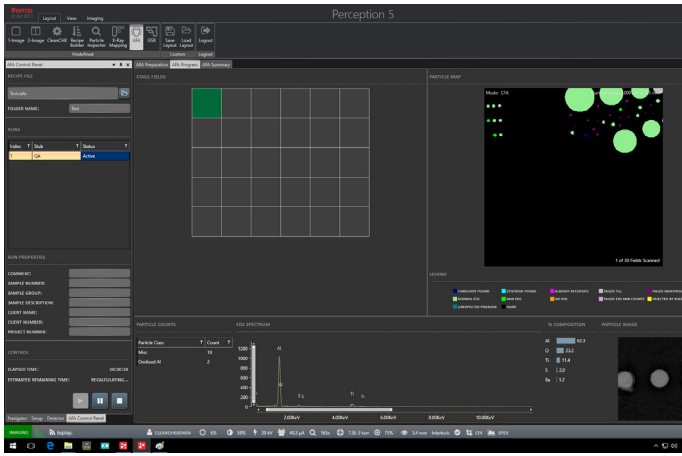
Elemental analysis is provided by EDX technology, which allows users to analyze the chemical composition of their samples. Detailed chemical composition can be obtained from a micro volume via a spot analysis. Elemental distribution can be visualized with the elemental mapping option.

#### **Elemental mapping and line scan**

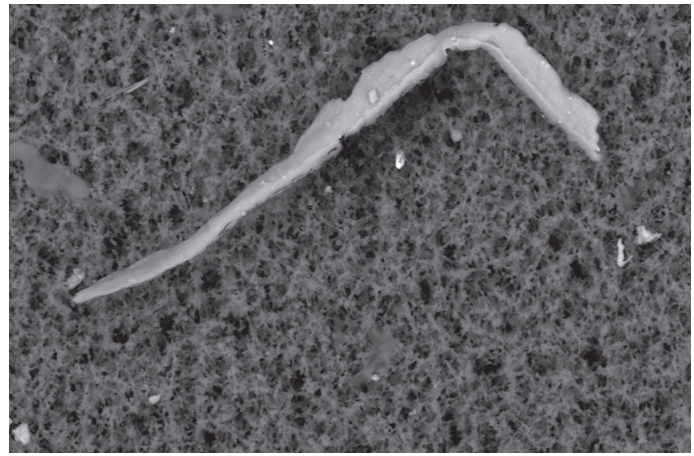
For the user, it is simply click and go to work with the elemental mapping and line scan functionality of the Phenom ParticleX Desktop SEM. The elemental mapping functionality visualizes the distribution of elements throughout the sample, and selected elements can be mapped at a user-specified pixel resolution and acquisition time. The real-time mapping algorithm shows live build-up of the selected elements. The line scan functionality shows the quantified element distribution in a line plot. This is especially useful for coatings, paints and other applications with multiple layers for analyzing edges, coatings, cross sections and other. Results of both the elemental mapping and line scan functionality can be easily exported by using an automated report template.

#### **Secondary electron detector**

A secondary electron detector (SED) is optionally available on the Phenom ParticleX Desktop SEM. The SED collects low-energy electrons from the top surface layer of the sample, making it the perfect choice to reveal detailed sample surface information. The SED can be of great use for applications where topography and morphology are important. This is often the case when studying microstructures, fibers or particles.



User interface ParticleX software.

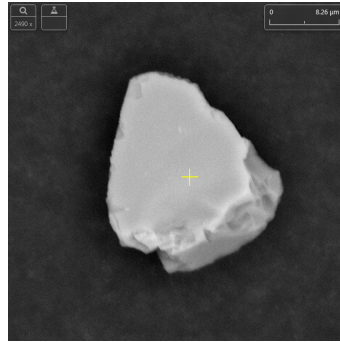


Example of aluminum wear debris.

### Phenom ParticleX Desktop SEM - Technical Cleanliness

With the growing demand for analysis of smaller particles beyond the scope of light microscopy within automotive industries, the Phenom ParticleX Desktop SEM - Technical Cleanliness enables automated Scanning Electron Microscopy with EDX Spectrometry. This is a major advantage over light microscopy as it enables chemical classification of the particles, providing great insights in your production processes and/or environments. Standard reports compliant with VDA 19 / ISO 16232 are available.

Industry-standard 47 mm filters can be automatically analyzed by starting an Automated Feature Analysis run. Standard recipes can be applied while specific parameters like particle size range, chemical classification rules, area of interest and stop criteria can be set for your application.



Revisit particles, e.g. Si rich.

Once the data is acquired, a report can be created according to automotive industry standards or user specific reports.

Afterwards, every particle can be revisited for further analysis.

File Template Page Setup Help

C:\AFAData\demo 1 filter 02-14-2019 002\Run\_1\Run\_1.hdz

SAMPLE INFORMATION		SAMPLE PREP INFORMATION		RUN INFORMATION	
Company:	Aspex	Component Surface By:	Volume	Magnification:	270x
Operator Name:	Joe	Volume of Extraction(cm <sup>3</sup> ):	100	Number of Stage Fields:	229
Part # / Sample ID:		Projected Volume(cm <sup>3</sup> ):	100	Area Scanned(mm <sup>2</sup> ):	31.41
Analysis Date:	2/14/2019 2:14:24 AM	Filter Size (mm):	300	Run ID's Present:	Run_1

ISO16232 / VDA-19 Results										
Size Class	B	C	D	E	F	G	H	I	J	K
Size Range (um)	5 ≤ X < 15	15 ≤ X < 25	25 ≤ X < 50	50 ≤ X < 100	100 ≤ X < 150	150 ≤ X < 200	200 ≤ X < 400	400 ≤ X < 600	600 ≤ X < 1000	1000 ≤ X
Misc Carbons	6	4	1	1						
Misc	14	11	1	1						
Steel	7	7						1		
Misc Salts	11	11								
Mineral	15	13	1	1						
Zn-P Coating	1	1								
Al <sub>2</sub> O <sub>3</sub>	1	1								
Glass	1	1								
Al Alloy	0									
Total Counts	59	49	3	3				1		

Particle Information

Individual Particle Parameters

STAGE MAP

REPORT TEMPLATES

ISO 16232 Standard

Particle Information

INCLUDE SECTION TITLE

INCLUDE HEADER

Extraction type: Volume

Volume Extracted in cm<sup>3</sup>: 100

Projected Volume in cm<sup>3</sup>: 100

Company Name: Aspex

Operator's Name: Joe

Filter Size in mm: 300

INCLUDE PARTICLE DATA

Normalize to search area 0 mm<sup>2</sup>

Normalize to extracted / oriented values

UPDATE

Report example according to ISO 16232 standards.\*

\*For other reports (e.g. ISO 4407), please contact your sales representative.

Imaging Specifications	
<b>Imaging modes</b>	
Light optical	Magnification range: 3 - 16x
Electron optical	<ul style="list-style-type: none"> <li>Magnification range: 80 - 100.000x</li> <li>Digital zoom max. 12x</li> </ul>
<b>Illumination</b>	
Light optical	Bright field / dark field modes
Electron optical	<ul style="list-style-type: none"> <li>Long lifetime thermionic source (CeB<sub>6</sub>)</li> <li>Multiple beam currents</li> </ul>
Acceleration voltages - Phenom UI	<ul style="list-style-type: none"> <li>Default: 5 kV, 10 kV and 15 kV</li> <li>Advanced mode: adjustable range between 4.8 kV and 20.5 kV imaging and analysis mode</li> </ul>
Vacuum levels	Low - medium - high
Resolution	<14 nm
Acceleration voltages Technical cleanliness EDX analysis	15 kV
<b>Detector</b>	
Standard	<ul style="list-style-type: none"> <li>Backscattered electron detector</li> <li>Energy Dispersive Spectroscopy detector</li> </ul>
Optional	Secondary electron detector
<b>Digital image detection</b>	
Light optical	Proprietary high resolution color navigation camera, single shot
Electron optical	High sensitivity backscattered electron detector (compositional and topographical modes)
<b>Image formats</b>	
JPEG, TIFF, BMP	
<b>Image resolution options</b>	
456 x 456, 684 x 684, 1024 x 1024 and 2048 x 2048 pixels	
<b>Data storage</b>	
USB flash drive, Network, Workstation	
<b>Sample stage</b>	
Computer-controlled motorized X and Y	
<b>Sample size</b>	
<ul style="list-style-type: none"> <li>Max. 100 mm x 100 mm (up to 36 x 12 mm pin stubs)</li> <li>Max. 65 mm (h)</li> </ul>	
<b>Scan area</b>	
<ul style="list-style-type: none"> <li>50 mm x 50 mm</li> <li>100 mm x 100 mm (optional)</li> </ul>	
<b>Sample loading time</b>	
Light optical	<5 s
Electron optical	<40 s

EDX Specifications	
<b>Hardware</b>	
Detector type	<ul style="list-style-type: none"> <li>Silicon Drift Detector (SDD)</li> <li>Thermoelectrically cooled (LN<sub>2</sub> free)</li> </ul>
Detector active area	25 mm <sup>2</sup>
X-ray window	Ultra thin Silicon Nitride (Si <sub>3</sub> N <sub>4</sub> ) window allowing detection of elements B to Am
Energy resolution	Mn Kα ≤132 eV
Processing capabilities	Multi-channel analyzer with 2048 channels at 10 eV/ch
Max. input count rate	300.000 cps
Hardware integration	Fully embedded
<b>Software</b>	
<ul style="list-style-type: none"> <li>Integrated column and stage control</li> <li>Auto-peak ID</li> <li>Iterative strip peak deconvolution</li> <li>Confidence of analysis indicator</li> <li>Export functions: CSV, JPG, TIFF, ELID, EMSA</li> </ul>	
<b>Report</b>	
Docx format	
<b>Elemental Mapping &amp; Line Scan Specifications</b>	
<b>Elemental Mapping</b>	
Element selection	10 individual user specified maps, plus backscatter image and mix-image
<b>Backscatter image and mix-range</b>	
Selected area	Any size, rectangular
Mapping resolution range	16 x 16 - 1024 x 1024 pixels
Pixel dwell time range	1 - 250 ms
<b>Line Scan</b>	
Line Scan resolution range	16 - 512 pixels
Points dwell time range	50 - 250 ms
Total number of lines	12
<b>Report</b>	
Docx format	
<b>SED Specifications</b>	
<b>Detector type</b>	
Everhart Thornley	

## System Specifications

### Dimensions & weight

Imaging module	316(w) x 587(d) x 625(h) mm, 75 kg
Diaphragm vacuum pump	145(w) x 220(d) x 213(h) mm, 4.5 kg
Power supply	156(w) x 300(d) x 74(h) mm, 3 kg
Monitor	531.5(w) x 515.4(h) x 250(d) mm, 6.7 kg
Workstation	169(w) x 456(d) x 432(h) mm, 15 kg

## Requirements

### Ambient conditions

Temperature	15°C ~ 30°C (59°F ~ 86°F)
Humidity	<80% RH
Power	Single phase AC 110 - 240 Volt, 50/60 Hz, 300 W (max.)

### Recommended table size

150 x 75 cm, load rating of 150 kg

### Workstation Specifications

- HP-PC Tower PC
- CPU Intel Xeon E5-1620
- RAM 16 GB
- SSD 2 x 1TB
- USB Keyboard; USB Mouse
- Microsoft Windows® 10 Enterprise Edition (64-bit)
- ParticleX Software pre-installed, full license code included
- ProSuite Framework pre-installed, full license code included- Automated Image Mapping- Remote UI

Distributore per l'Italia:



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